


Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Complete If Known	
				APPLICATION NUMBER	10/747,737
				FILING DATE	12/29/2003
				FIRST NAMED INVENTOR	Bailey et al.
				Group Art Unit	1756
Sheet 6 of 7				Examiner Name	Unassigned
				Attorney Docket Number	PA97-39D13D21

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²

EC	C66	Colburn et al., Step and Flash Imprint Lithography: A New Approach to High-Resolution Patterning, Proc. Of SPIE, vol. 3676, 3/1/1999	
	C67	Heldari, Nanoimprint Lithography at the 6 in. Wafer Scale, J. Vac. Sci. Technol. B 18(6), pp. 3557 - 3560, 11/1/2000	
	C68	Translation of Japanese Patent 02-92603 4/3/90	
	C69	Translation of Japanese Patent 02-24848 1/26/90	
	C70	Chou et al., Ultrafast and Direct Imprint of Nanostructures in Silicon, Nature, Vol. 417, (June 2002), pp. 835-837, 6/1/2002	
	C71	Chou et al., Nanoimprint Lithography, Journal of Vacuum Science Technology B 14(16), pp. 4129-4133, 11/1/1998	
	C72	Colburn et al., Development and Advantages of Step-and-Flash Lithography, Solid State Technology, 7/1/2001	
	C73	Colburn et al., Characterization and Modeling of Volumetric and Mechanical Properties for Step and Flash Imprint Lithography Photopolymers, Journal of Vacuum Science Technology. Vol b. 19(6), 11/1/2001	
EC	C74	Bailey et al., Step and Flash Imprint Lithography: Defect Analysis, Journal of Vacuum Science, B 19(6), pp. 2808-2810, 11/1/2001	

Examiner Signature		Date Considered	5/15/06
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*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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EC	C75	Bailey et al., Step and Flash Imprint Lithography: Template Surface Treatment and Defect Analysis, Journal of Vacuum Science, B 18(6), pp. 3572-3577, 11/1/2000	
EC	C78	Schneider et al., Stripes of Partially Fluorinated Alkyl Chains: Dipolar Langmuir Monolayers 5/1/05	

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